

<b>PATENT ASSIGNMENT COVER SHEET</b>
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<b>SUBMISSION TYPE:</b>	NEW ASSIGNMENT
<b>NATURE OF CONVEYANCE:</b>	ASSIGNMENT
<b>CONVEYING PARTY DATA</b>	
<b>Name</b>	<b>Execution Date</b>
WEI-WEN TSAI	05/02/2017
LIN-CHEN HO	05/02/2017
CHENG-PING LEE	05/02/2017
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<b>State/Country:</b>	DELAWARE
<b>Postal Code:</b>	19713
<b>PROPERTY NUMBERS Total: 1</b>	
<b>Property Type</b>	<b>Number</b>
<b>Application Number:</b>	16335552
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<b>ATTORNEY DOCKET NUMBER:</b>	DI79736
<b>NAME OF SUBMITTER:</b>	PATRICIA A. CONNELL
<b>SIGNATURE:</b>	/Patricia A. Connell/
<b>DATE SIGNED:</b>	04/26/2019
<b>Total Attachments: 1</b>	
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**ASSIGNMENT**

We/I, the undersigned

Wei-Wen Tsai, of Taipei, Taiwan; Lin-Chen Ho, of Taichung, Taiwan and Cheng-Ping Lee, of Miaoli County, Taiwan

Hereby declare that

We/I are true and first inventor(s) of an invention relating to

CHEMICAL MECHANICAL POLISHING METHOD FOR TUNGSTEN

which is disclosed in PCT International Application Number PCT/CN2016/100709 filed on the 29<sup>th</sup> day of September, 2016 (Docket No. 79736) which designates States including the United States of America; and, for valuable consideration, the receipt and adequacy of which is hereby acknowledged and in fulfillment of our pre-existing obligation of assignment, we hereby sell, assign and transfer unto Rohm and Haas Electronic Materials CMP Holdings, Inc., a corporation organized and existing under the laws of the State of Delaware in the United States of America and having its mailing address at 451 Bellevue Road, Newark, Delaware, hereinafter referred to as the assignee, the entire right, title, and interest in and to the aforesaid PCT International Application, including any priority rights derived from the aforesaid PCT International Application by virtue of the International Convention for the Protection of Industrial Property for any and all member countries of the aforesaid International Convention, and the entire right, title and interest in and to any and all our inventions, whether joint or sole, disclosed in the aforesaid PCT International Application, and in and to any and all applications for letters Patent for any such inventions in any country whatsoever, and in and to any and all patents for any such inventions in any country whatsoever, with the sole right to file such applications in its name or ours, including the sole right to file such applications under the aforesaid International Convention, together with the sole right to have said patents granted in its name or ours and to enforce said patents and to sue for and recover profits and damages for any and all infringements thereof, and hereby agree, whenever requested, to communicate to us respecting said inventions, to testify in any legal proceeding, to execute all applications, papers, or instruments necessary or required by said assignee, its successors, assigns, and legal representatives to carry into effect any of the provisions of this instrument, and generally to do everything possible to aid said assignee, its successors, assigns and legal representatives to obtain and enforce proper patent protection for said inventions in any and all countries.

IN WITNESS WHEREOF, We have hereunto signed our names on the day and year set forth below.

Wei-Wen Tsai  
Wei-Wen Tsai

5/2/2017  
DATE

Lin-Chen Ho  
Lin-Chen Ho

2017/5/2  
DATE

Cheng-Ping Lee  
Cheng-Ping Lee

2017/5/2  
DATE